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COMMISSIONER FOR PATENTS
UNITED STATES PATENT AND TRADEMARK OFFICE
WASHINGTON, D.C. 2023
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BIBDATASHEET

Bib Data Sheet

CONFIRMATION NO. 8409

SERIAL NUMBI 10/085,753			CLASS 134		GROUP ART UNIT 1746		ATTORNEY DOCKET NO. TI-31620	
APPLICANTS								
Toshihito Tsuga,	Tsuct	niura-shi, JAPAN;						
Minoru Fube, Hayami-gun, JAPAN; Kazutaka Nakayama, Hayami-gun, JAPAN; ** CONTINUING DATA **********************************								
MK (Verified) FOREIGN APPLICATIONS								
IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 03/27/2002								
Foreign Priority claimed					HEETS TOTAL		AL	INDEPENDENT
Verified and Acknowledged	Exan	niner's Signature Ir	COUNTRY JAPAN	DF	AWING 2	CLAI		CLAIMS 2
ADDRESS 23494 TEXAS INSTRUMENTS INCORPORATED P O BOX 655474, M/S 3999 DALLAS , TX 75265								
TITLE Method and device for removing particles on semiconductor wafers								
	FEES: Authority has been given in Paper Noto charge/credit DEPOSIT ACCOUNT Nofor following:				☐ All Fees			
FILING FEE					1.16 Fees (Filing) 1.17 Fees (Processing Ext. of			
					time)			
870					☐ 1.18 Fees (Issue)			
					☐ Credit			